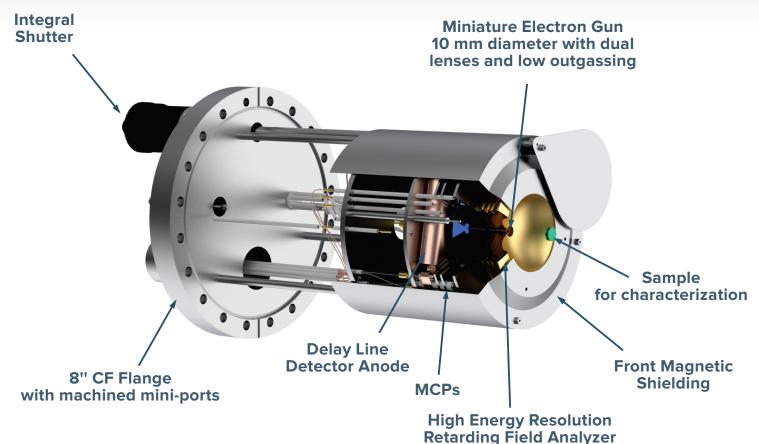
Surface Crystallography Spectrometer

based on Low Energy Electron Diffraction (LEED) with Delay-Line Anode and Microchannel Plates

FemtoLEED, Model DLD-L800



Features:

-Fully digital image acquisition

-No fluorescent screen

-Dual 80 mm Microchannel Plates (MCP)

-Primary electron beam in the range of femto ampere

-Electron diffraction on insulating single crystal samples

-Large coherence width

-Superior magnetic shielding

-Integral Shutter



Retarding Field Anal

Applications

The FemtoLEED, Model DLD-L800 is specifically useful for investigations on ultra-sensitive and insulating single crystals substrates with organic epitaxial films.

The fully digital system negates the need for an external CCD camera for live image capture.

Materials suitable for characterization should be single crystals and epitaxial films in categories such as: 2D materials, semiconductors, metals, oxides and magnetic films.

Canada: 200 Stronach Cres., London, Ontario, N5V3A1 USA: 6405 Inducon Drive West, Sanborn (Niagara County), NY, 14132 TEL. (519) 457-0878, FAX (519) 457-0837 E-mail: info@ocivm.com Website: www.ocivm.com

FemtoLEED, Model DLD-L800

Specifications

INTEGRAL MINIATURE ELETRON GUN Beam Energy

Ordering Guide

Beam Current

Electron Source Energy Spread

Beam Size

Overall Size

DLD-L800

LMX-EXT

LPS075-D

MCPS2

DLA-TR8

DLD-LIM32

ISH

FemtoLEED (Model DLD-L800)

Detector	Delay Line Detector with dynamic range 32 bit per channel, 75 μ m spatial resolution and active area diameter 145x145 mm 77° angle of acceptance from sample Microchannel Plates Electron gain: 10 ⁷ , operating in pulsed mode	U
Retarding Field Analyzer	Concentric assembly of hemispherical grids Working distance from sample 15 mm	м
Grid Material	Gold coated tungsten wire mesh (100 mesh, 81% transparency)	
Energy Resoulution	0.2%	i.
Linear Motion	External nipple with bellow up to 150 mm retraction	
Integral Shutter	Open and close at any position of the linear motion	D
Magnetic Shielding	Mu-metal cylinder with front cover for maximum magnetic field attenuation	
Assembly	Extreme-high-vacuum compatibility with	
Mounting	stainless steel, high alumina and gold-plated copper alloy materials 8"(DN150CF) conflat flange with port length range 145 mm - 580 mm	Ē
Bakeability	Under vacuum, 250°C maximum	

LEED - 5 eV to 750 eV

From 300 µm to 100 µm

Tungsten-2%Thoriated filament standard, Single crystal LaB6 filament optional

10 mm lens diameter and 80 mm length

LEED optics with 2 microchannel plates, delay line detector and axial electron gun on 8" CF

Digital power supply with voltage range 0 - 750 V

Controller for delay line detector and computer

Delay line detector acquisition software and LEED analysis software for Windows 10

0.45 eV (thoriated-tungsten filament)

External linear motion (nipple-bellow)

Controller for microchannel plates with overvoltage and overcurrent protection

Range from nA to fA

(CF150) flange

Integral shutter

interface PCI card

(X=retraction distance)

Control Electronics

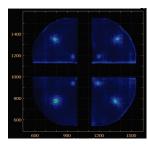
- **LPS075-D** Digital LEED power supply (0-750 V) with USB interface and PC control software for Windows 10. True primary beam current and total emission measurements. Automatic start-up and shut down, 10 memory settings including standby and outgassing mode with a timer, constant beam current mode.
- MCPS2 Electronics for two microchannel plates with digital displays of voltages and MCP load current measurements and protection.

LEED Software

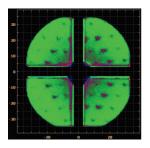
DLD-LIM32 LIM-DLD LEED pattern measurements and analysis software and hardware for Windows 10 including: •Automatic LEED pattern acquisition •Automatic I-V analysis with spot tracking •Automatic I-T analysis •Automatic spot profile analysis

Data

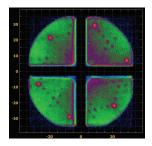
MgO(100) - Beam Energy 10 eV and 100 eV



Si (111) - Beam Energy: 10 eV



Si (111) - Beam Energy: 50 eV



Schematic Drawings

